L	Hits	Search Text	DB	Time stamp
Number				
3	3330	(control near gate) and (source and drain) and memory and (ONO	USPAT; US-PGPUB;	2004/09/21
		(oxide-nitride-oxide)	EPO; JPO;	
		(oxide/nitride/oxide) (silicon near	DERWENT;	
		oxide/silicon near nitride/silicon near oxide)) and (@ad<20030514 @rlad<20030514)	IBM_TDB	
4	533630		USPAT;	2004/09/21
		film)) SOI (silicon near on near	US-PGPUB;	13:50
}		insulator)	EPO; JPO;	
			DERWENT;	
			IBM_TDB	
5	3048	((control near gate) and (source and	USPAT;	2004/09/21
		drain) and memory and (ONO	US-PGPUB;	13:53
		(oxide-nitride-oxide)	EPO; JPO;	
		(oxide/nitride/oxide) (silicon near	DERWENT;	1
1		oxide/silicon near nitride/silicon near oxide)) and (@ad<20030514 @rlad<20030514)	IBM_TDB	
) and (((insulat\$3 dielectric) near		
		(layer film)) SOI (silicon near on near		
	<u> </u>	insulator))		